

Docket No. F-6971

RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2882

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

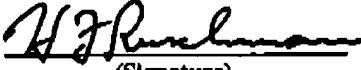
Applicant	:	Sciichi HAYASHI, et al.	
Serial No.	:	09/852,111	
Filed	:	May 9, 2001	
For	:	METHOD AND APPARATUS FOR MEASURING THIN FILM, AND THIN FILM DEPOSITION SYSTEM	
Group Art Unit	:	2882	RECEIVED
Examiner	:	Hoon K. Song	CENTRAL FAX CENTER
Confirmation No.	:	5010	SEP 28 2004
Customer No.	:	000028107	

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AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR 1.116

Docket No. F-6971

Scr. No. 09/852,111

INTRODUCTORY COMMENTS:

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SEP 28 2004

Sir:

In response to the final Office Action of June 30, 2004, entry of the present amendment to place the application into condition for allowance or remove issues from appeal, if required, is respectfully requested. Please amend the above-identified patent application as follows: